



# High Spatial Resolution MEMS Surface Pressure Sensor Array for Transonic Compressor IGV Measurement

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#### Outline



- Introduction
- IGV Instrumentation
  - -Research Facility
  - -Previous Instrumentation
  - -Flex Circuit Substrate
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  - -Multiplexer Array
  - -Trimmer Circuits & Static Calibration
- Preliminary Measurements
- Conclusions



#### Introduction & Motivation

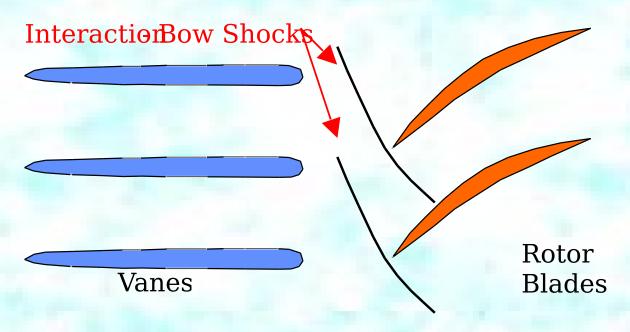


- Forced response is an important component of HCF analysis
  - Vane/blade interaction a principal cause of unsteady aerodynamics
  - Detailed measurements required to determine flow physics
- Shock interaction is a main driver in unsteady aerodynamics
  - Insight into bow shock flow physics is needed
  - Shock/boundary layer interaction in end-wall region is unknown
- MEMS technology is utilized to understand flow physics
  - Increased economical measurement resolution required
  - Decreased installation expense due to MEMS flex circuit technology



#### Introduction





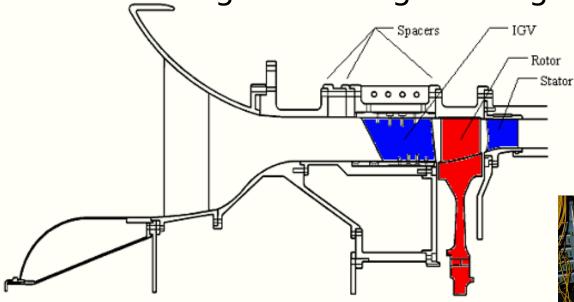
- Bow shocks are the primary unsteady driver
- High spatial & frequency resolution data is required to understand the complicated flow physics involved



## Research Facility

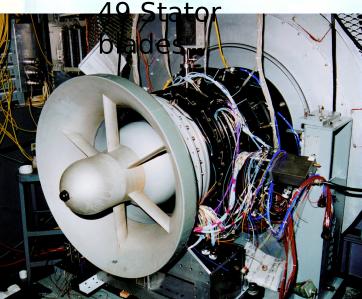


Compressor Aero Research Laboratory (CARL)
Stage Matching Investigation (SMI) Rig



3 possible IGV/Rotor spacings: 12, 26, 56% IGV Chord (0.36", 0.75", 1.68")

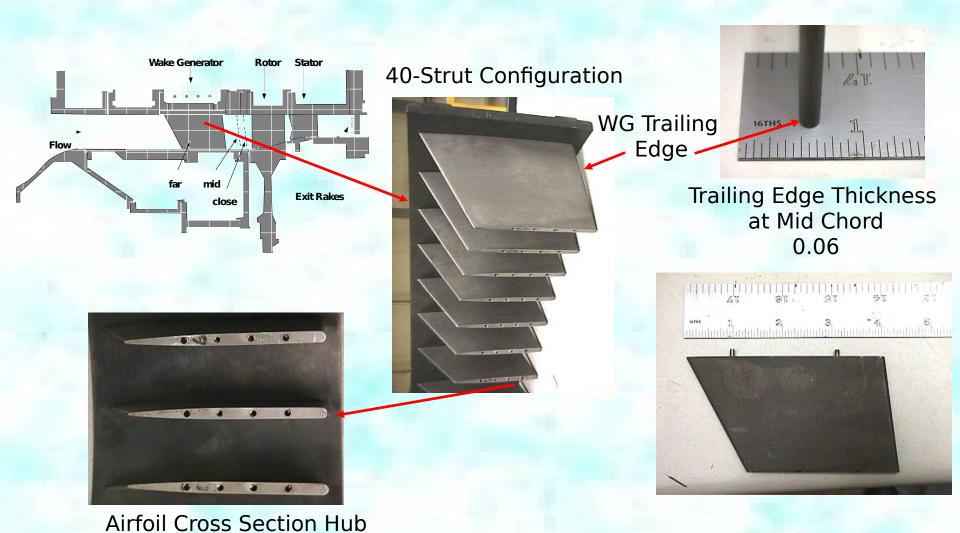
12, 24, 40 IGV's 33 Rotor blades





## Inlet Guide Vane (IGV)

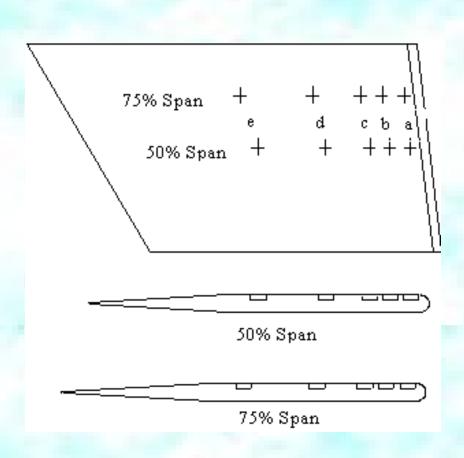


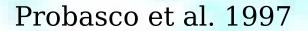


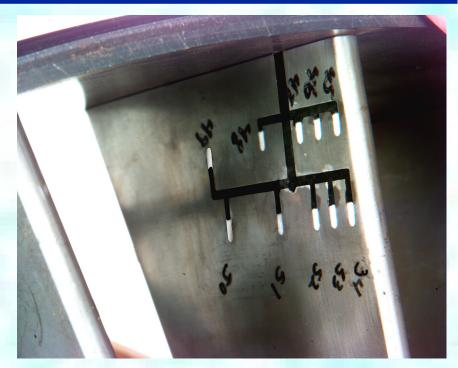


#### **Previous Instrumentation**







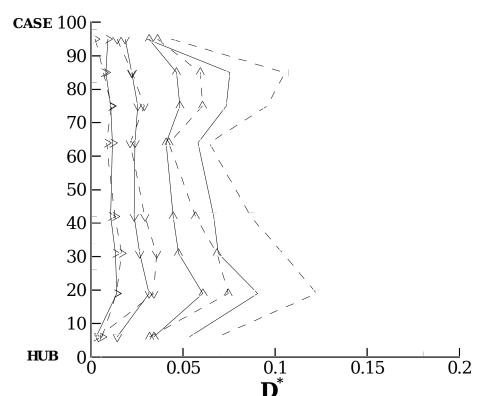


- 10 Kulite LQ-125 pressure transducers
- 25 psia
- 95%, 89%, 83%, 70%,
  50% chordwise locations
- \$25,000



#### 3-D Flow Field



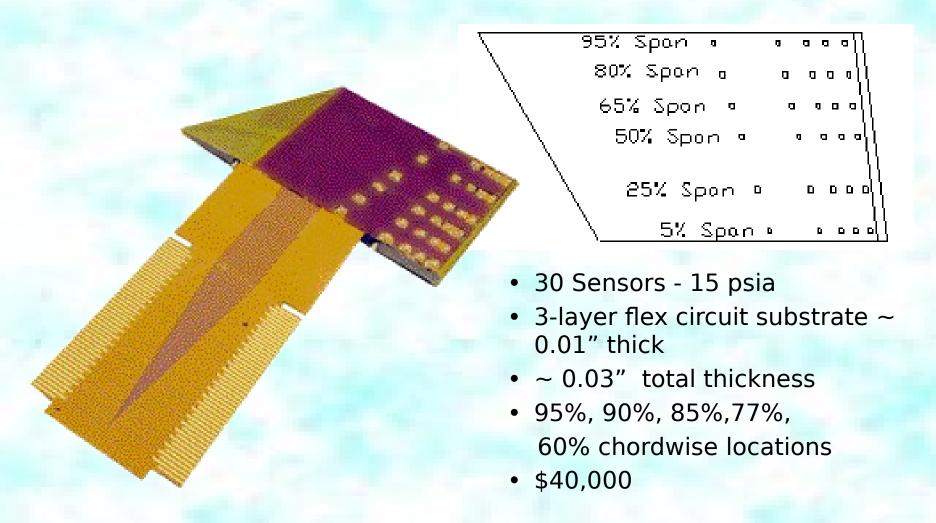


Vortical forcing function research by Koch et al.
 2000 demonstrates the 3-D nature of flow in the SMI rig



## **MEMS** Sensor Array

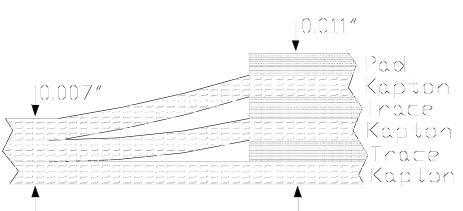




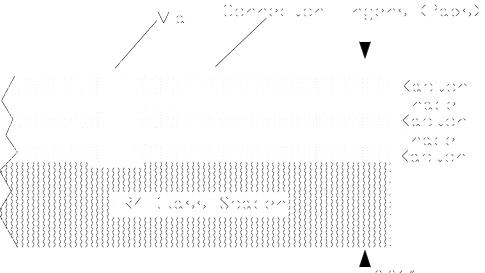


## Flex Circuit Substrate





Substrate layers

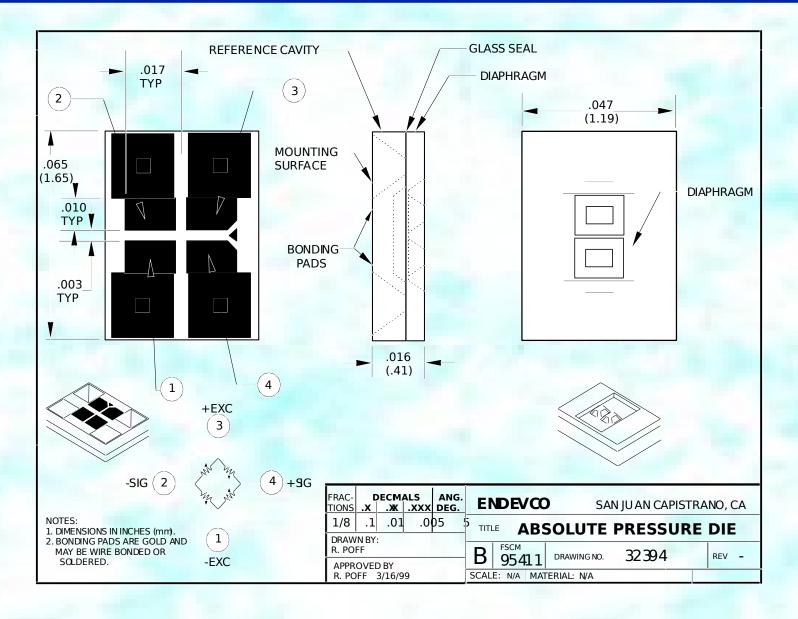


Outside of the test section



#### Pressure Transducer Dies

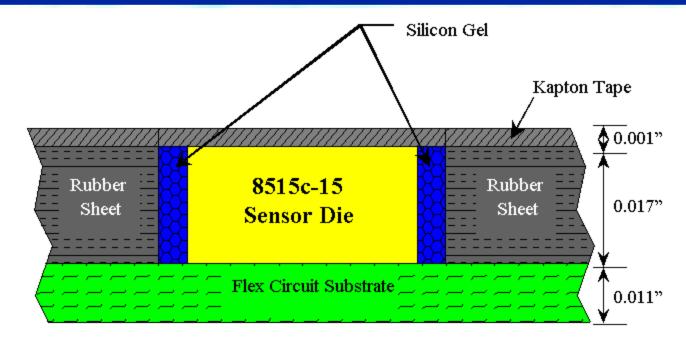






# Sensor Application



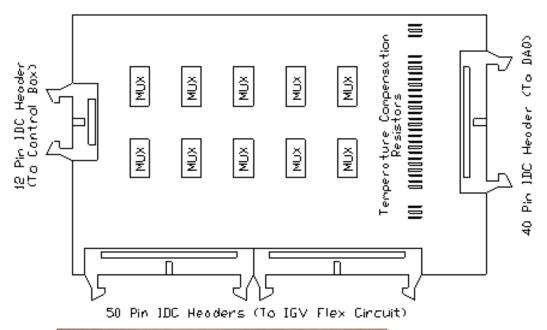


- 30 mil slot machined in IGV
- Rubber sheet fills between sensor dies
- Silicon gel & kapton tape used to contour surface



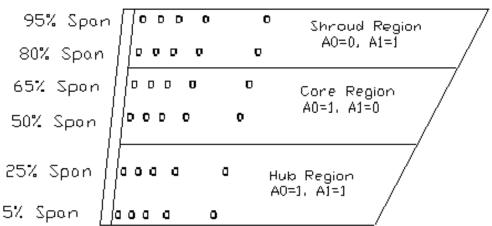
## Multiplexed Array





- 2-Board design (stackable)
- 10 MUX/board
- Incorporates thermal compensation resistors
- Remotely controllable

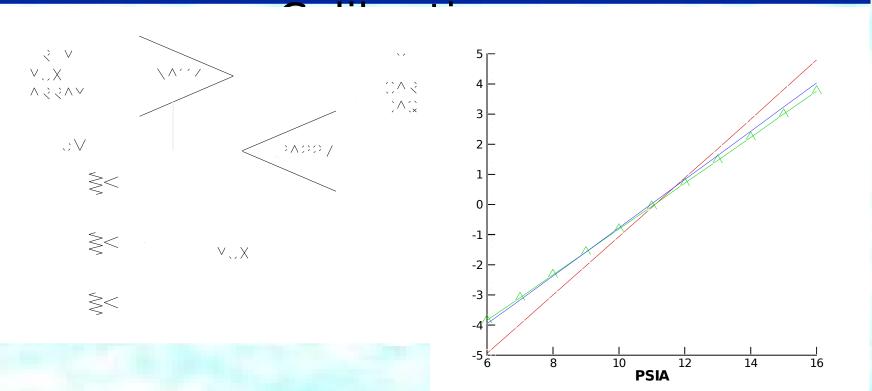






#### **Trimmer Circuit &**





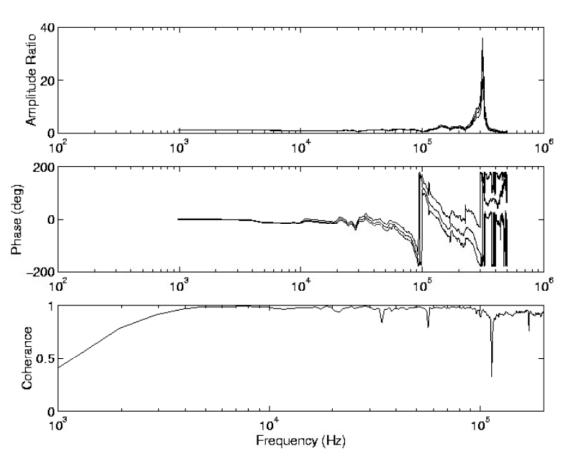
- Incorporation of the trimmer circuits allowed for a full DC signal to be obtained with the existing CARL DAQ system
- Static calibration showed excellent linearity of the MEMS

pressure sensor array system



# **Dynamic Calibration**





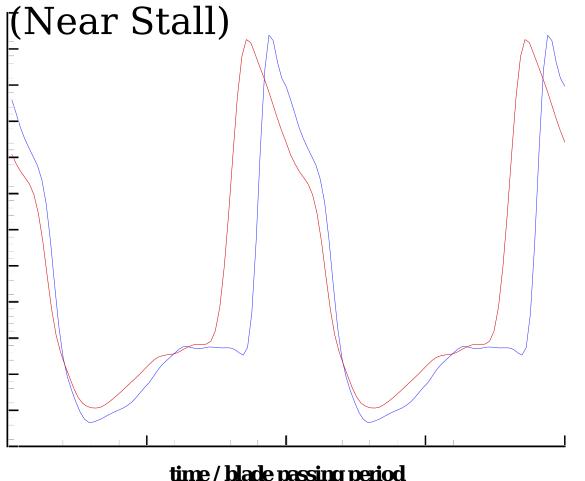
- WSU Shock Tube Testing
- Usable Frequency BW 30 kHz



#### Comparison with Kulite



#### 50% Span, 95% Chord, 105% Speed



- Favorable agreement with previous sensor data
- Slight phase shift caused by annular shift in physical sensor location

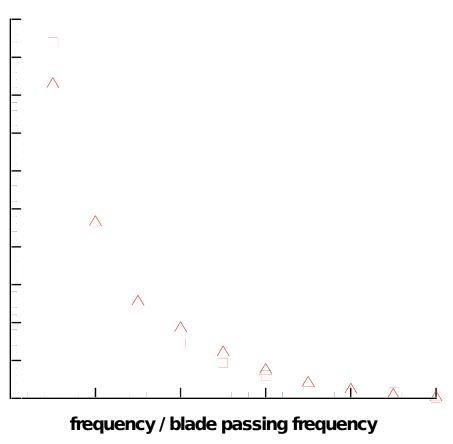
time / blade passing period



# **Preliminary**



#### Measurements



- 50% Span, 90% Chord,
  105% Speed
- 8% variation in 1st harmonic amplitude
- Differences caused by uncertainty in matching test conditions with different ambient conditions



# **Summary & Conclusions**



- MEMS Sensors Designed and Installed
  - 2 IGV blades instrumented 60 total sensors
  - High spatial and temporal resolution
  - AC and DC pressure components obtained
- High-speed transonic compressor unsteady aerodynamics data
  - Excellent agreement with previous traditional sensors
  - Tip region flow physics including shock/boundary layer interaction measured
  - Spacing and throttle position influences were measured